

Title: Method of Fabricating Semiconductor Device and Wafer Treatment Apparatus Employed Therefor as
well as Semiconductor Device
Inventors: SHINTANI ET AL.
Atty Docket No.: 401352
Leydig, Voit & Mayer, Ltd. 202-737-6770

FIG.1

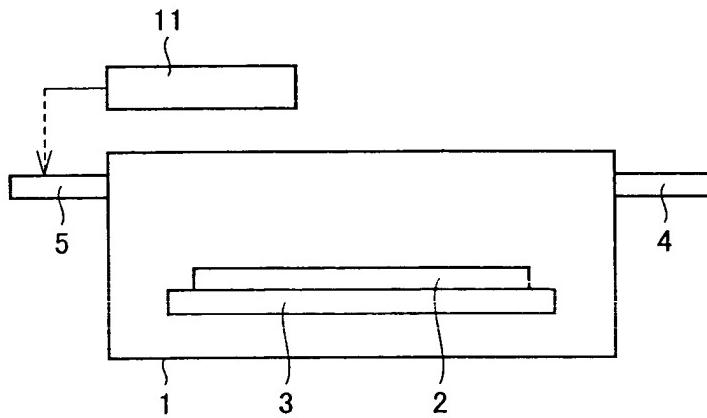


FIG.2

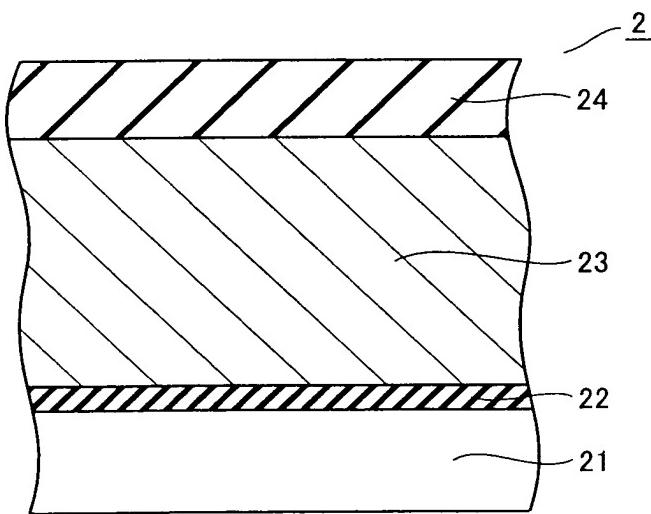


FIG.3

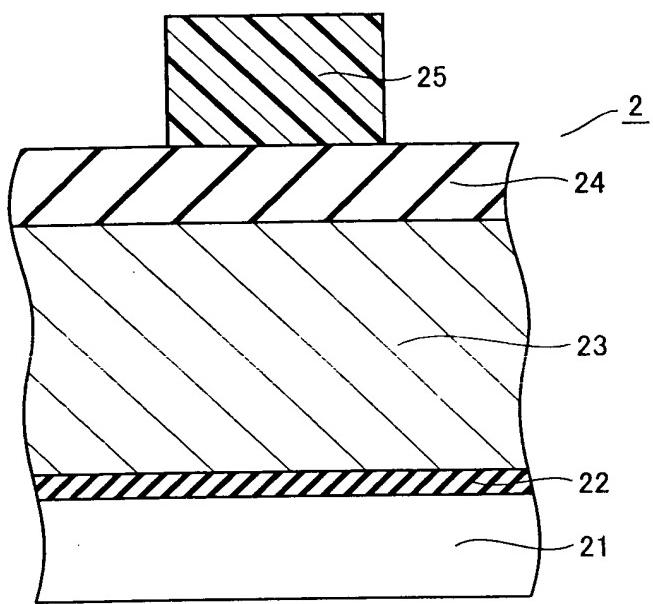


FIG.4

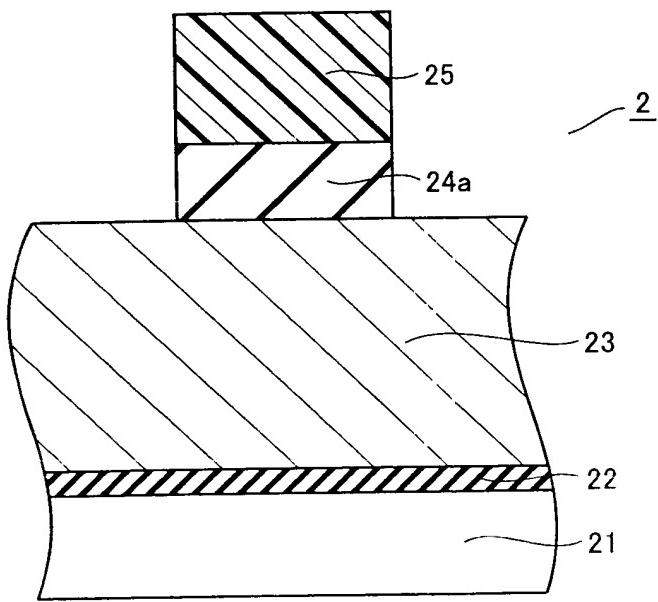


FIG.5

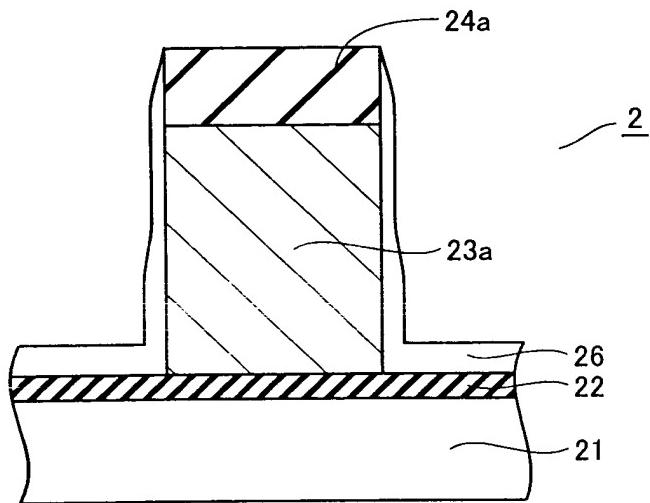


FIG.6

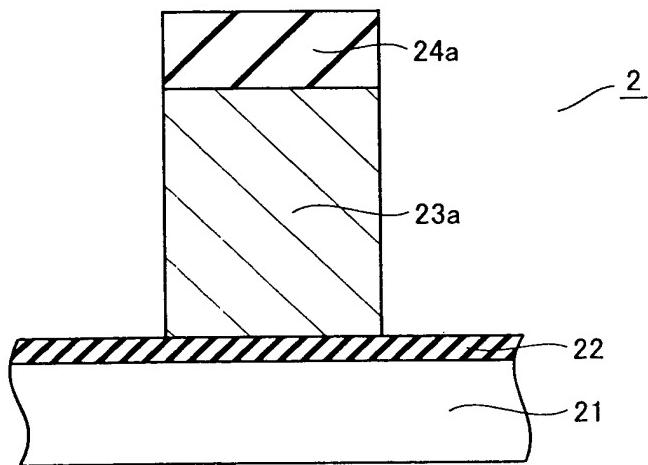


FIG.7

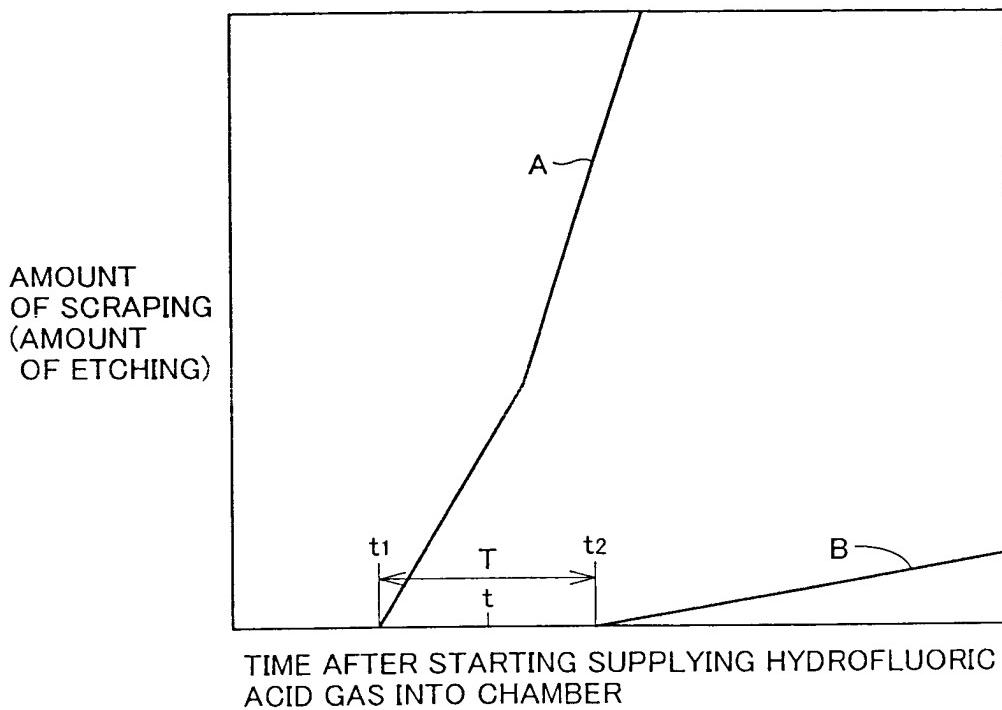


FIG.8

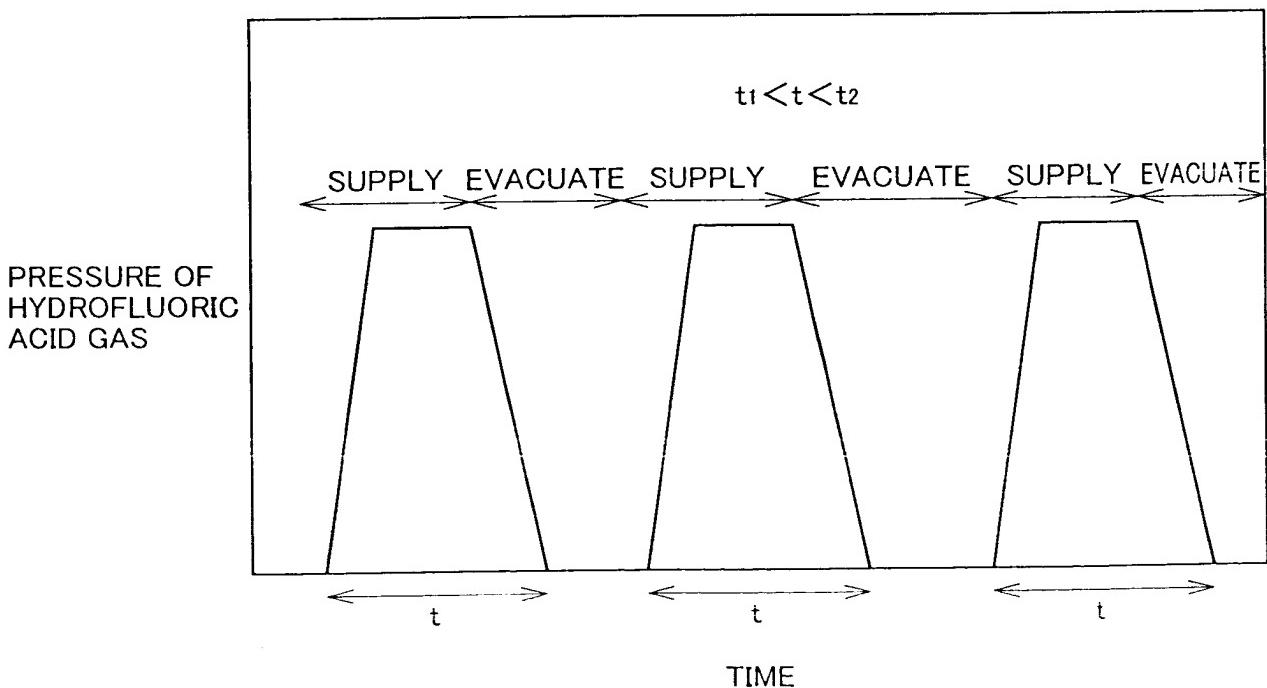


FIG.9

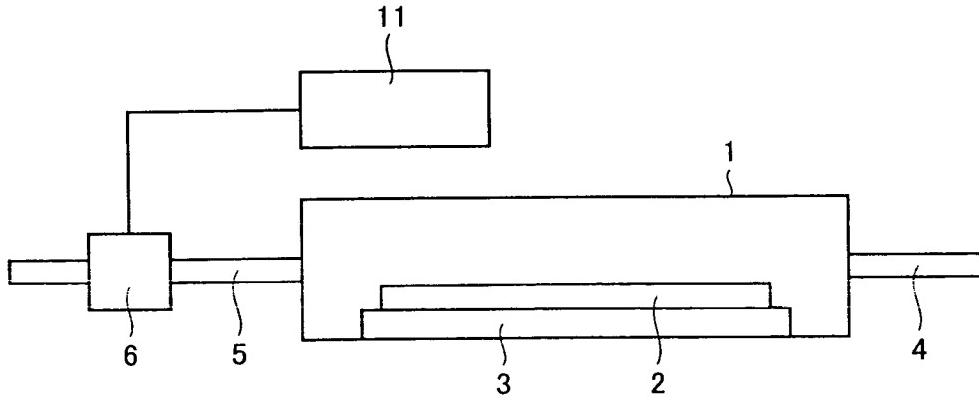


FIG.10

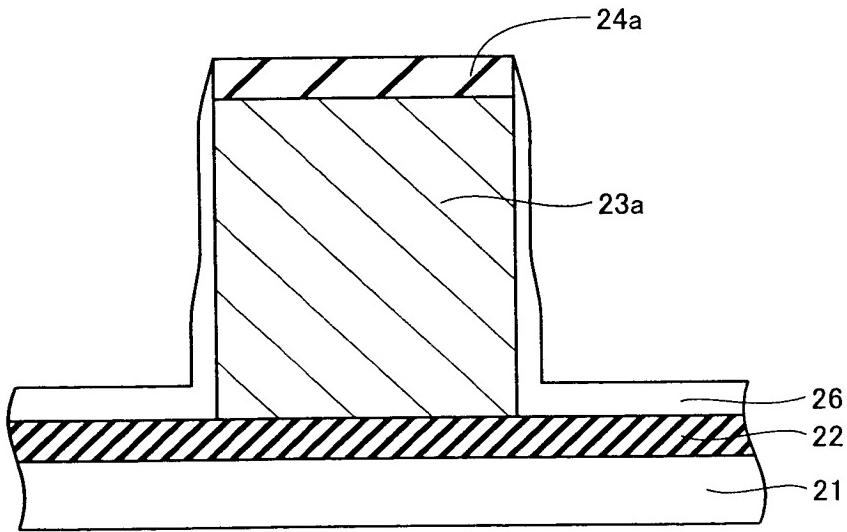


FIG.11

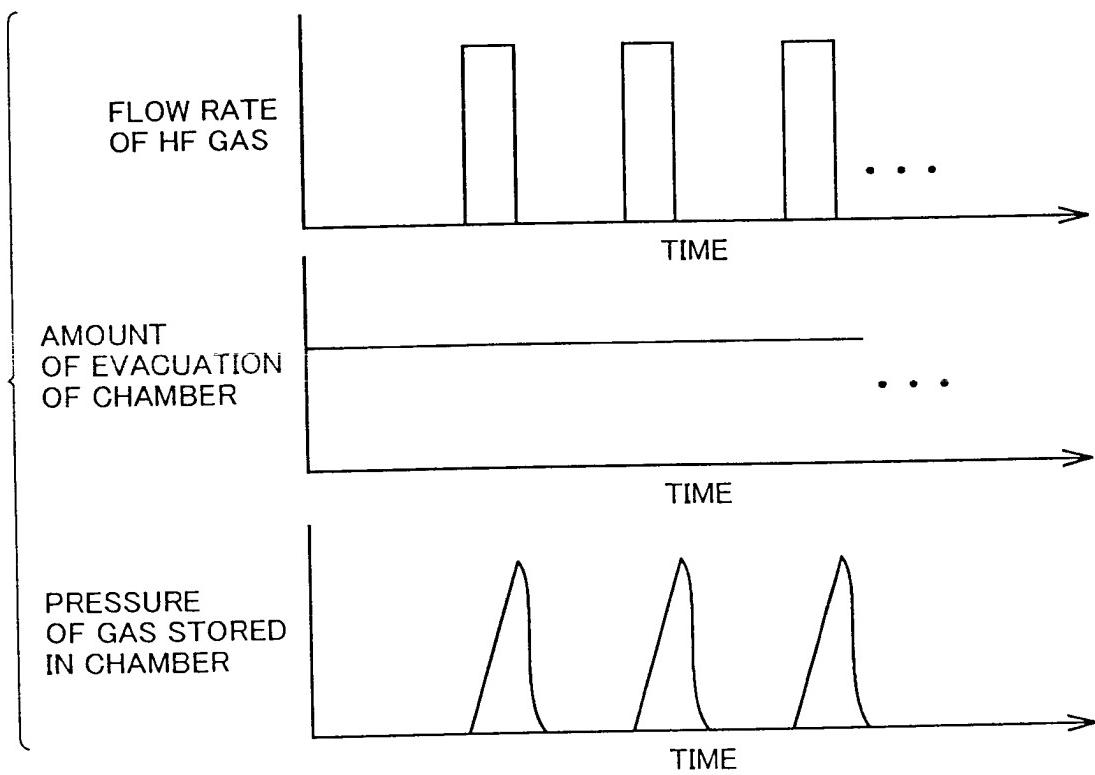


FIG.12

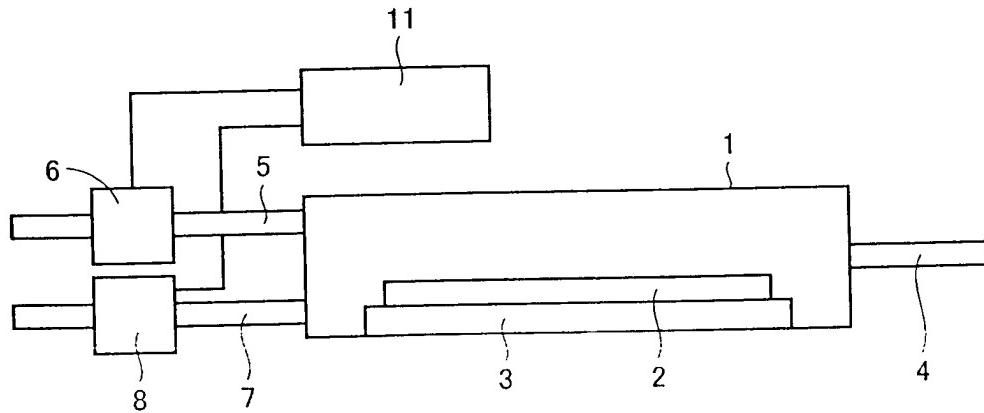


FIG.13

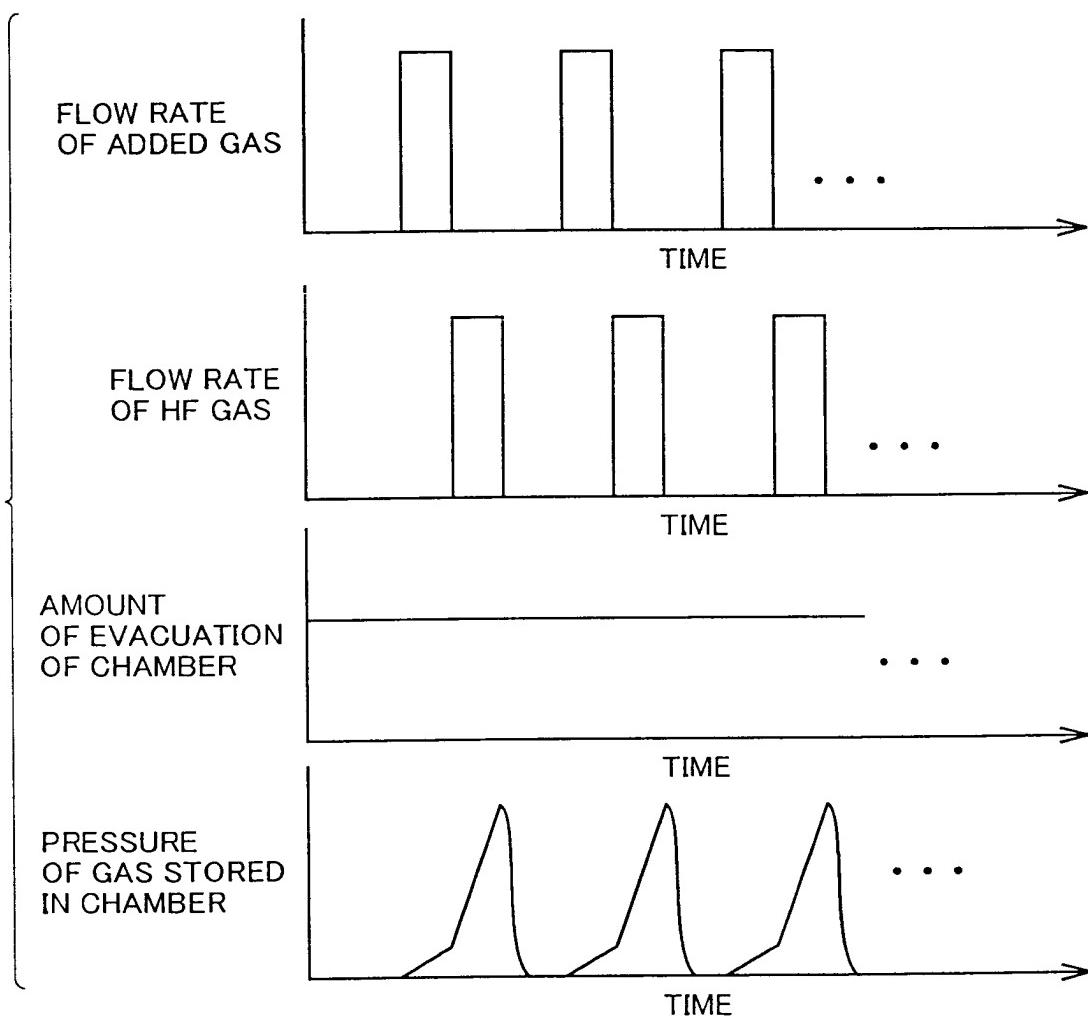


FIG.14

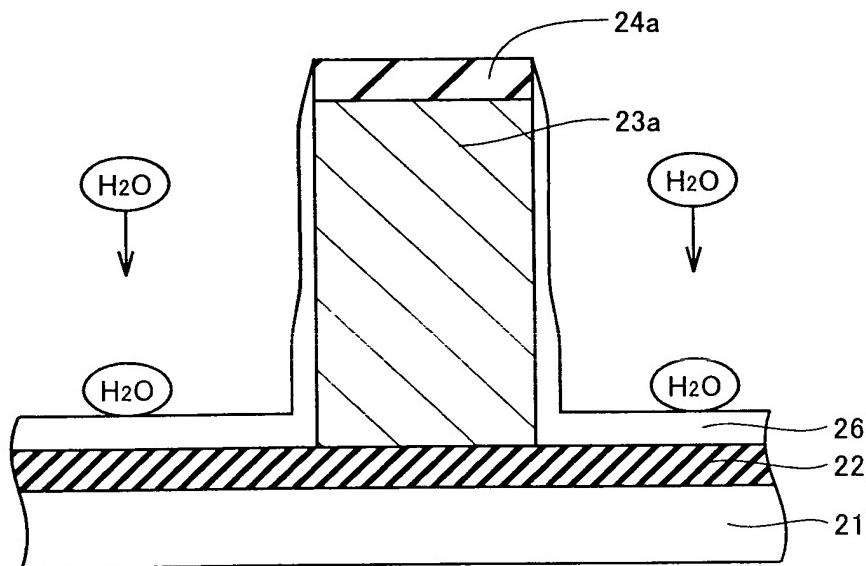


FIG.15

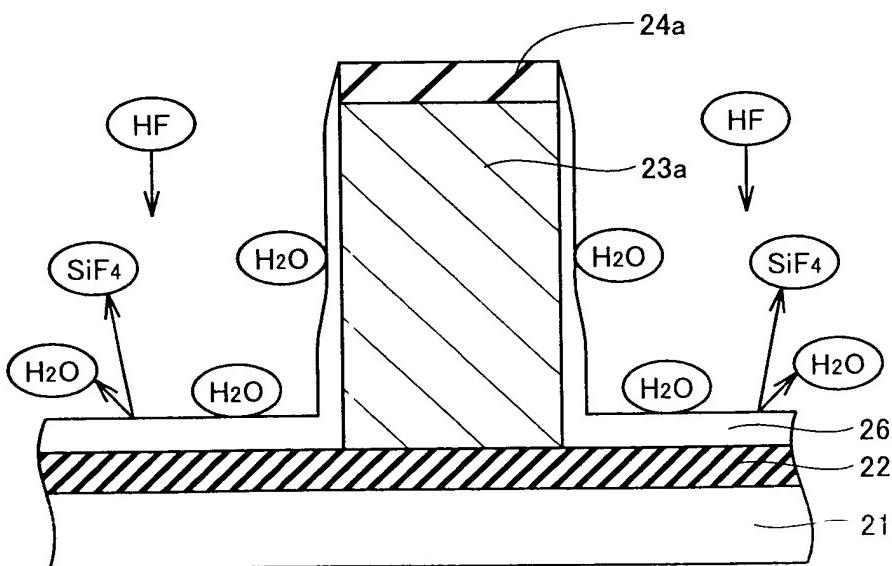


FIG.16

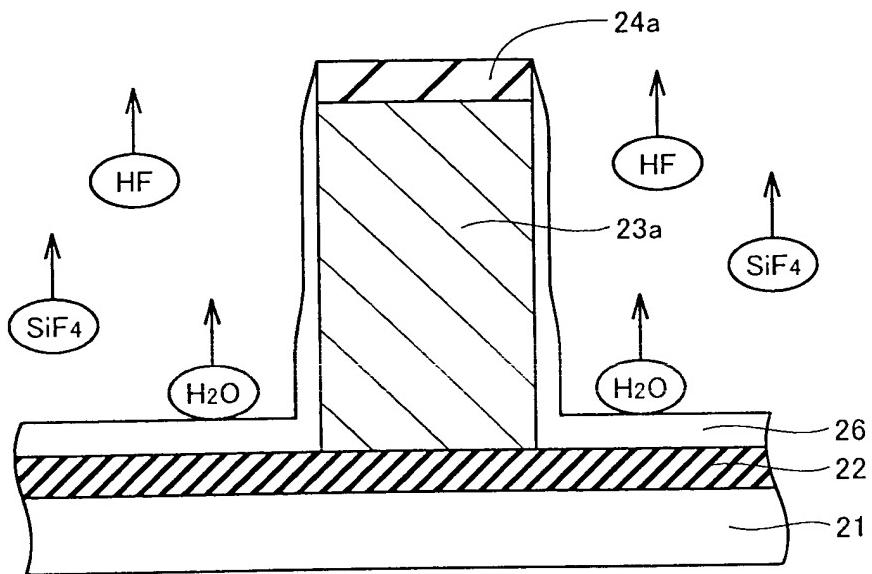


FIG.17

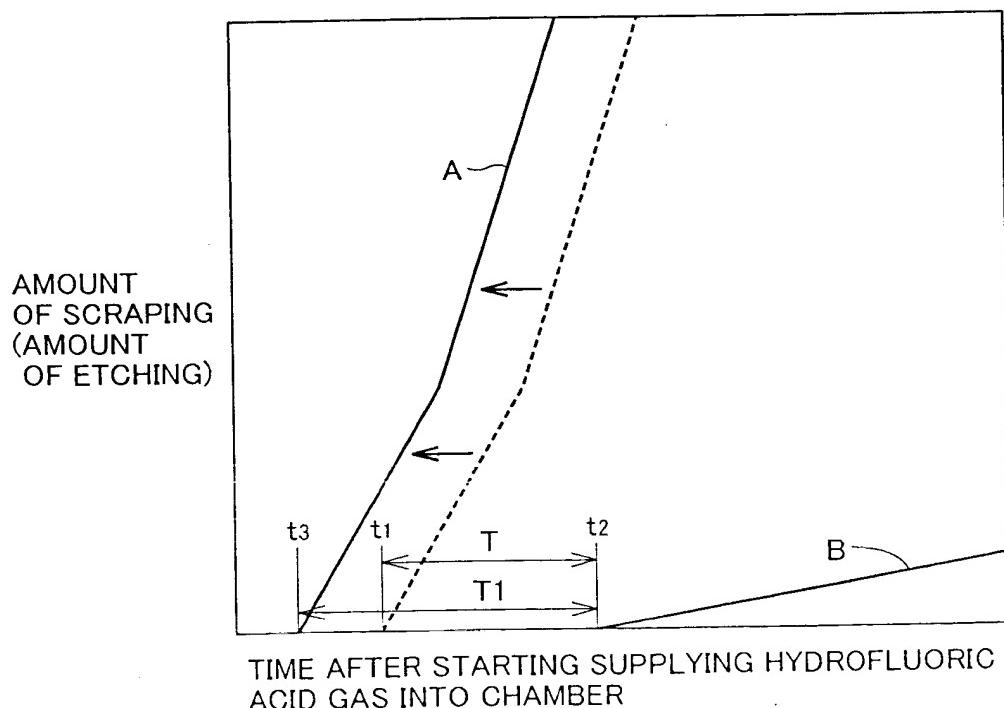


FIG.18

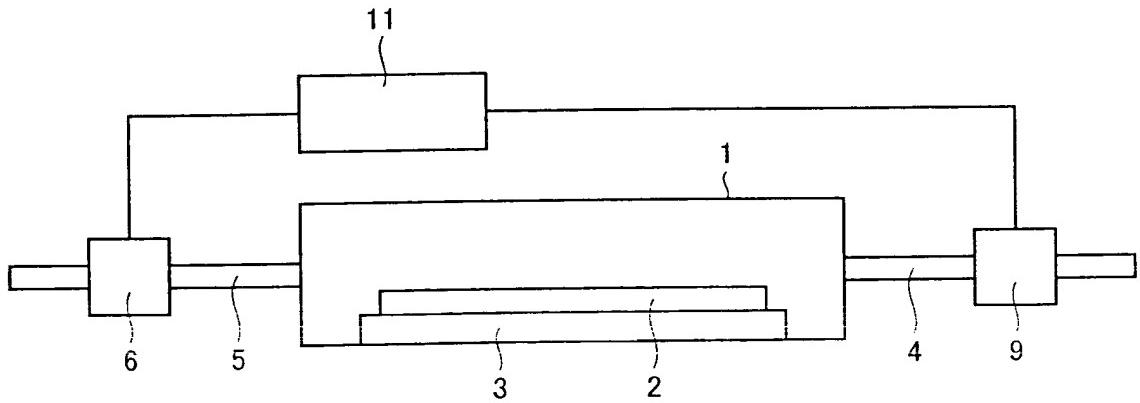


FIG.19

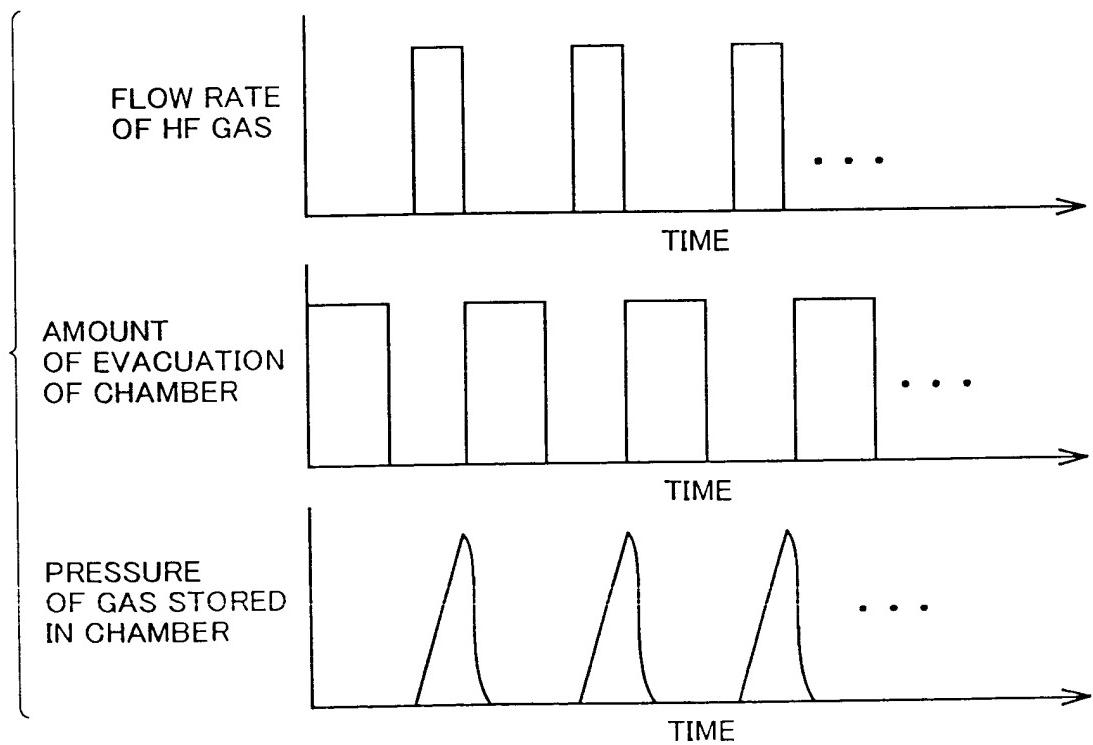


FIG.20

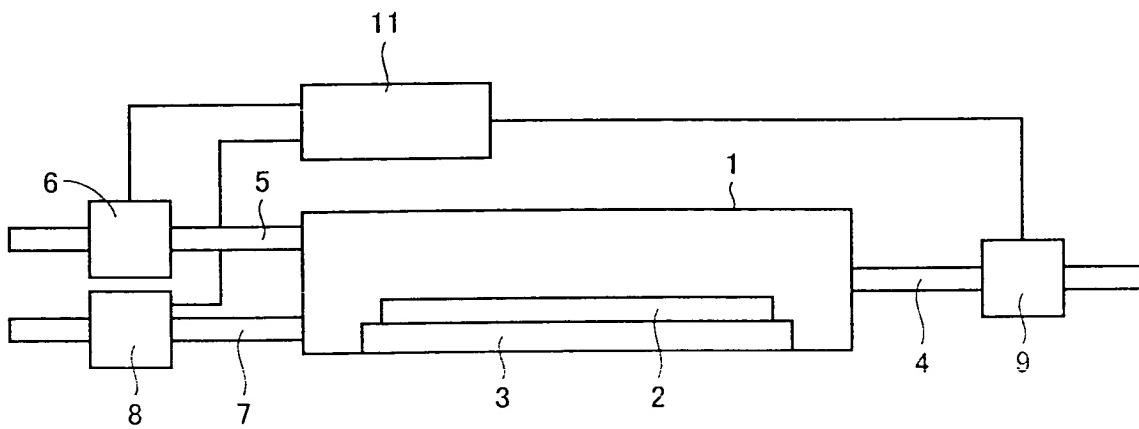


FIG.21

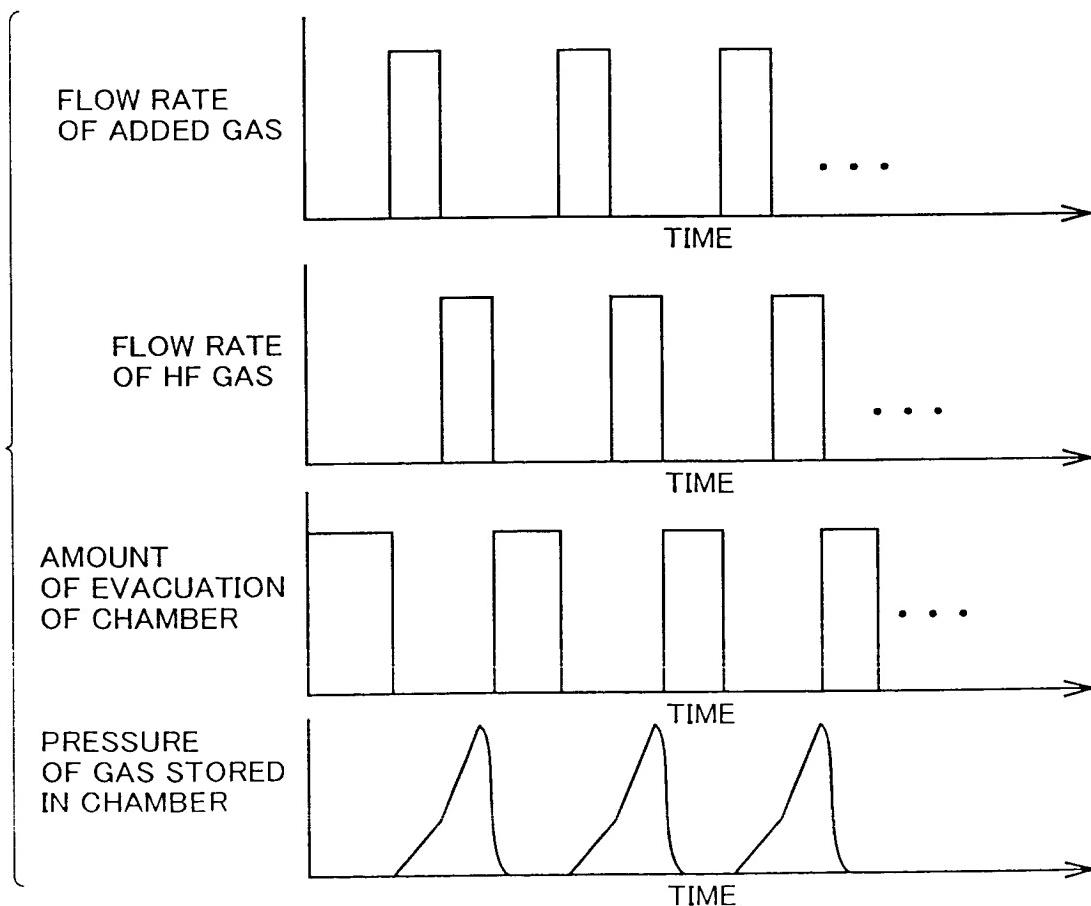


FIG.22

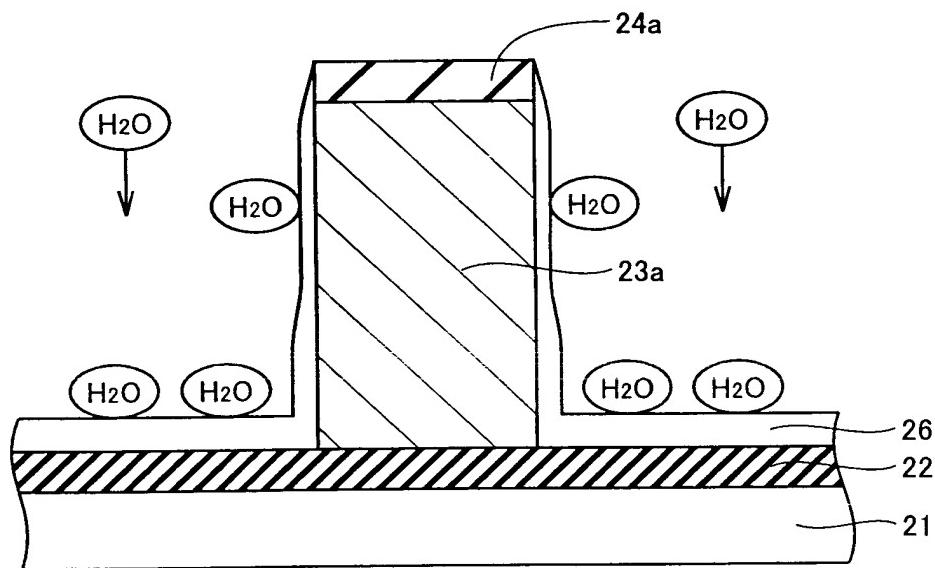


FIG.23

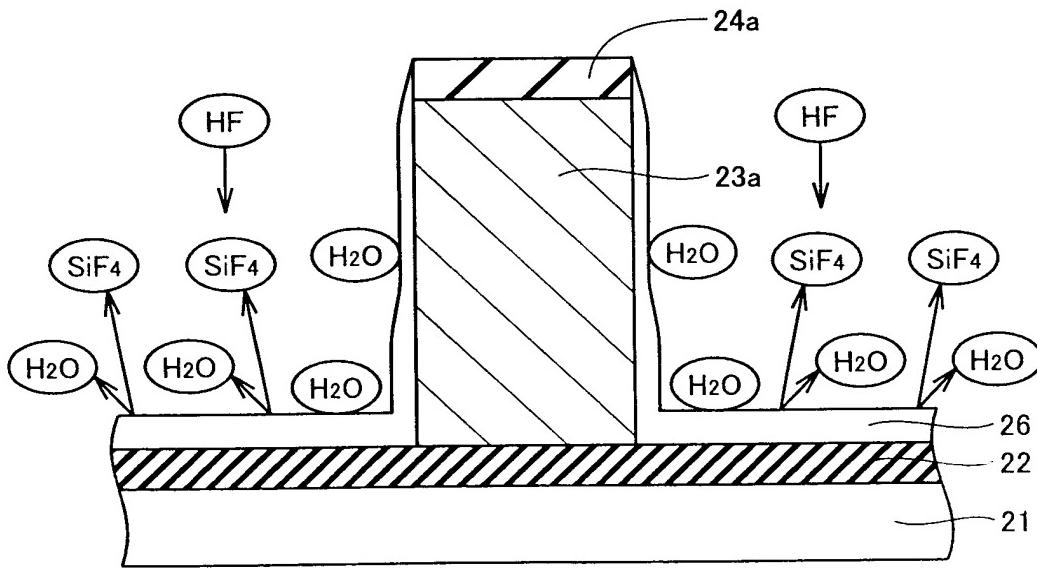


FIG.24

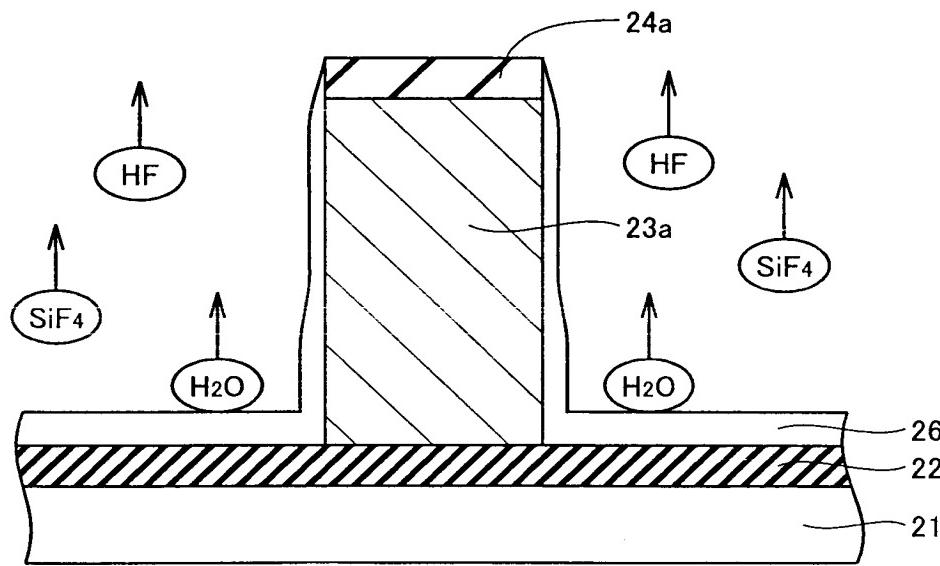
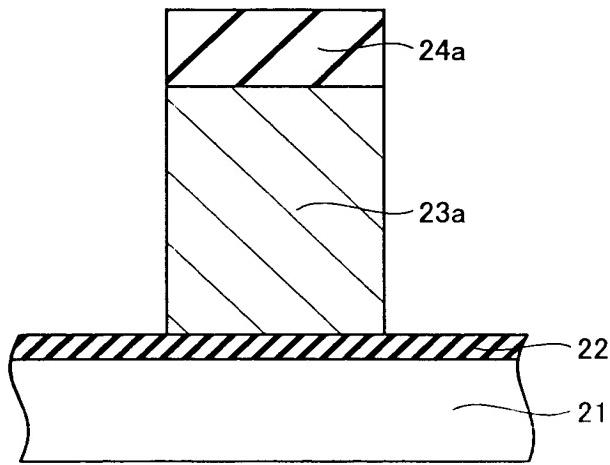


FIG.25



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FIG.26

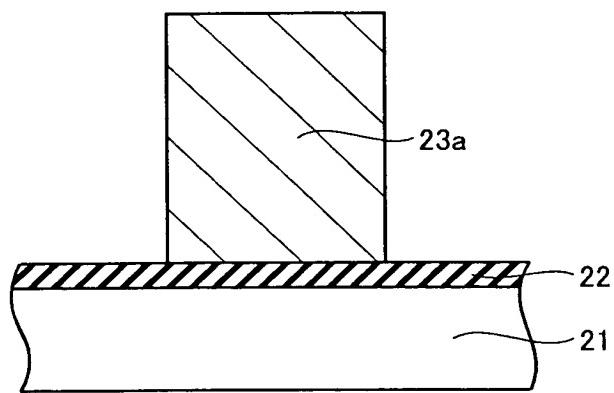


FIG.27 PRIOR ART

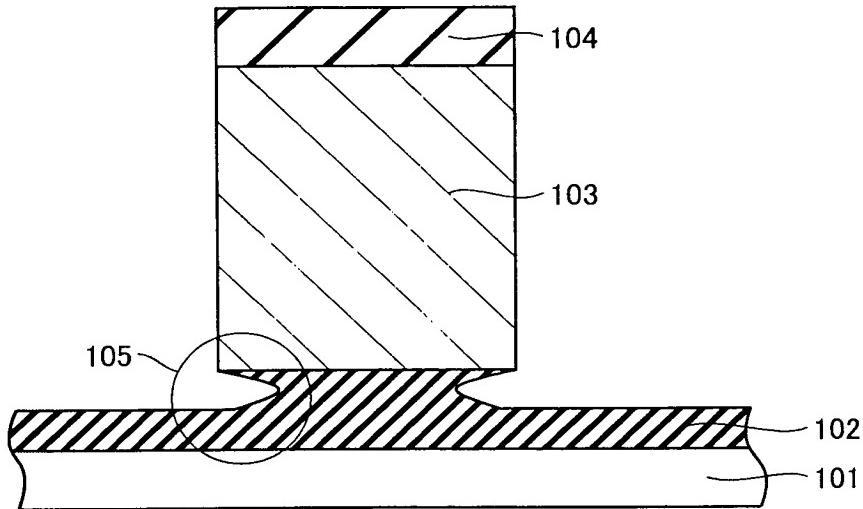
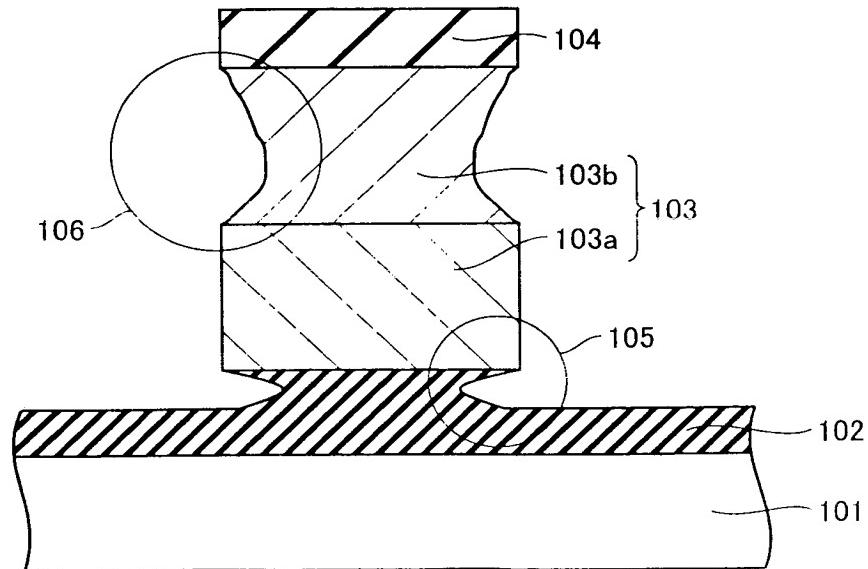


FIG.28 PRIOR ART



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FIG.29 PRIOR ART

